



THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Shih, et al

Group Art Unit: 3743

Serial No.: 09/410,896

Examiner: L. Ciric

Filed: October 2, 1999

In Response to Office Action

Dated: November 6, 2001

For: Apparatus And Method For Cooling A
Semiconductor Substrate

Attorney Docket No.: 67,200-207

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I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Box AF, Assistant Commissioner for Patents, Washington, D.C. 20231.

Kathy Dixon

Date: January 3, 2002

REQUEST FOR RECONSIDERATION

Box AF
Assistant Commissioner
for Patents
Washington, D.C. 20231

Dear Sir:

In response to a final Office Action mailed November 6, 2001, please enter the following amendments and consider the following remarks.